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Jana Kovačičinová
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Introduction

The Institute of Plasma Physics of the CAS, v.v.i. (Czech Republic) has regularly organized the Optics and Measurement International Conference to share knowledge and experience gained in the field of research and development of optical elements, systems, and measurement methods. The conference is an opportunity to link the industrial and academic communities specialized in the above-mentioned field of optics.

The main topics of the Optics and Measurement International Conference 2019 were selected based on the latest technology and experience and focused on:

- design, production, and machining of optical elements from standard and non-standard materials using the latest procedures and technology;
- methods and systems for optical measurement; characterization of optical elements by interferometric, holographic, and other methods;
- computational and hyperdimensional imaging, technology of thin films deposition and its measurement;
- fine mechanics (construction and technology of mechanical parts and system manufacturing for using in optics);
- optical elements and advanced systems for highly specific application (radiation hard optics, x-ray and laser optics, diffractive optics and HOE elements, optical systems for space, etc.).

Since 2012, interesting scientific work and industrial applications have been presented at a high professional level at the Optics and Measurement International Conference. We believe that the conference continues to contribute to the establishment of new partnerships between the participating organizations.

Jana Kovačičinová